Dr Mohammad Abdur Rashid



Jashore University of Science and Technology

Dr Rashid, 2022

Silicon Wafer Production

https://www.youtube.com/watch?v=AMgQ1-HdEIM

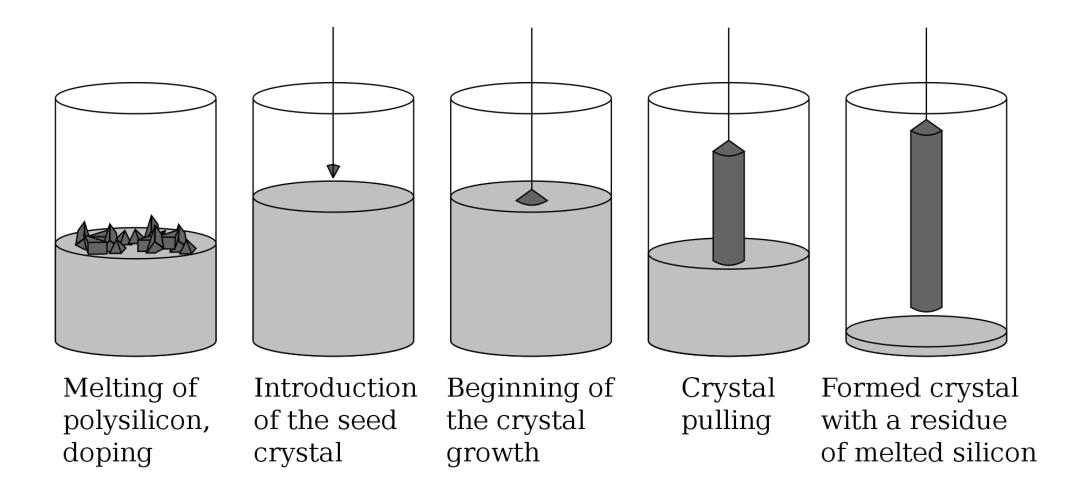


Jashore University of Science and Technology

The time it takes to grow a silicon ingot varies, depending on many factors. More than 75% of all single crystal silicon wafers grow via the Czochralski (CZ) method. CZ ingot growth requires chunks of virgin polycrystalline silicon. These chunks are placed in a quartz crucible along with small quantities of specific Group III and Group V elements called dopants. The added dopants give the desired electrical properties for the grown ingot. The most common dopants are boron, phosphorus, arsenic, and antimony. Depending on the dopant, the ingot becomes a P or N type ingot (boron: P type; Phosphorus, antimony, arsenic: N type).



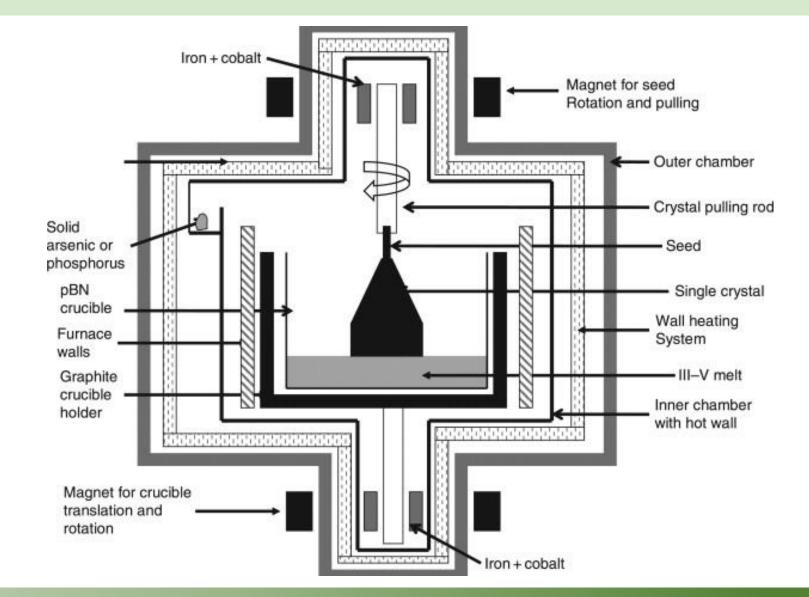
The Czochralski method





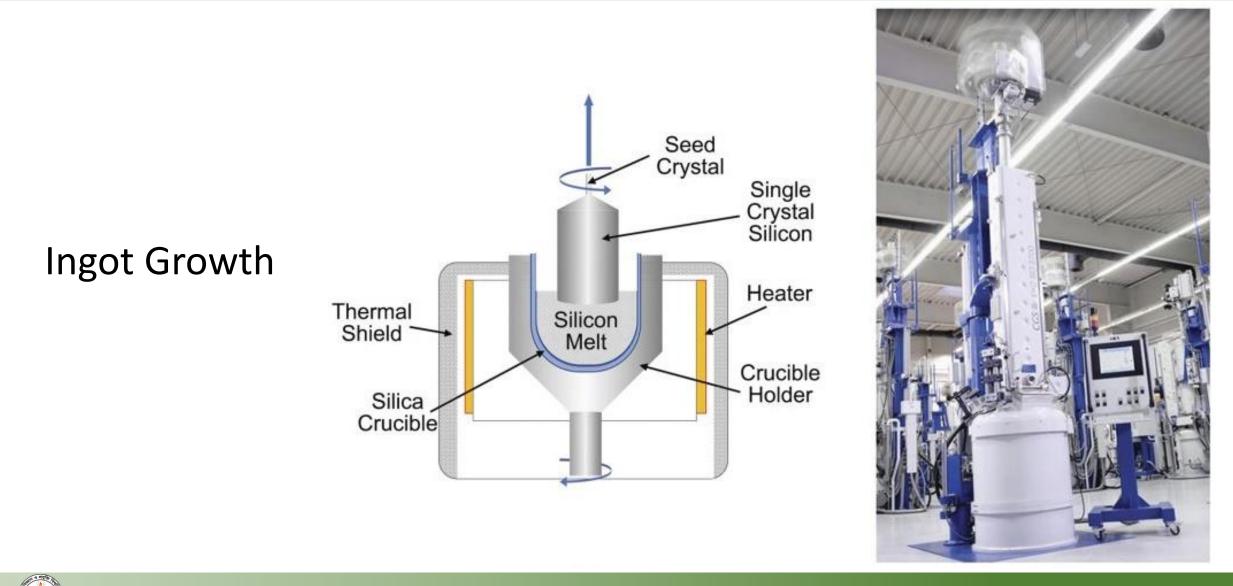
4

The Czochralski method





Jashore University of Science and Technology

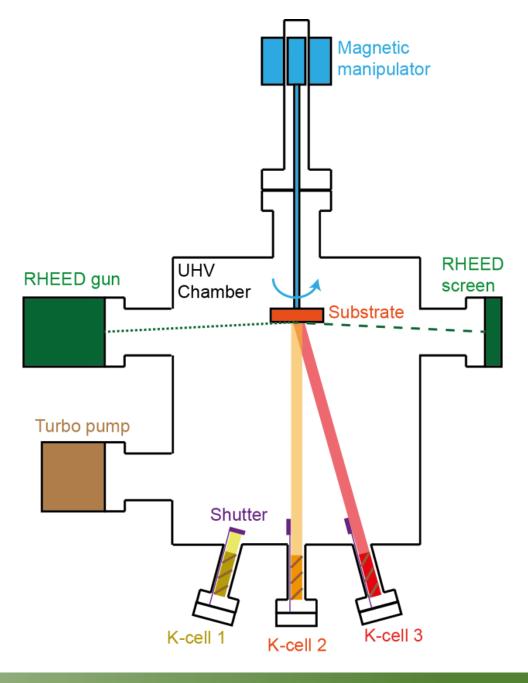


Silicon Wafer Production Process

https://www.sas-globalwafers.co.jp/eng/products/wafer/process.html

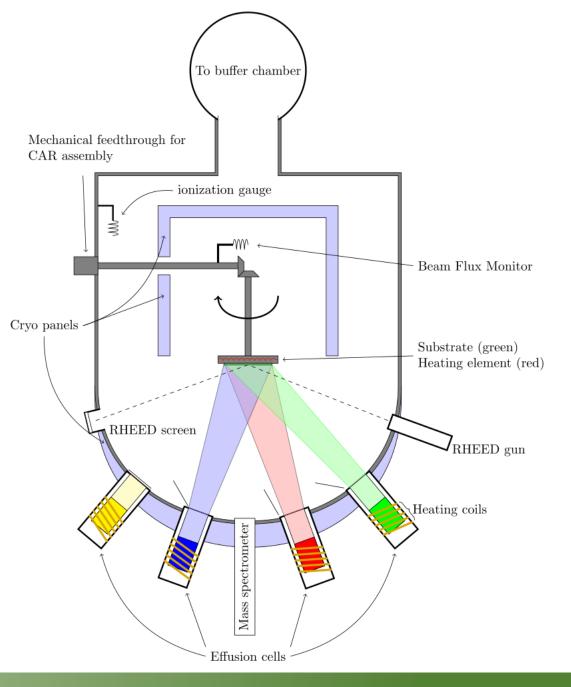


Molecular Beam Epitaxy (MBE)





Molecular Beam Epitaxy (MBE)







- Silicon Wafer Production (The Czochralski method)
- Molecular-beam epitaxy

